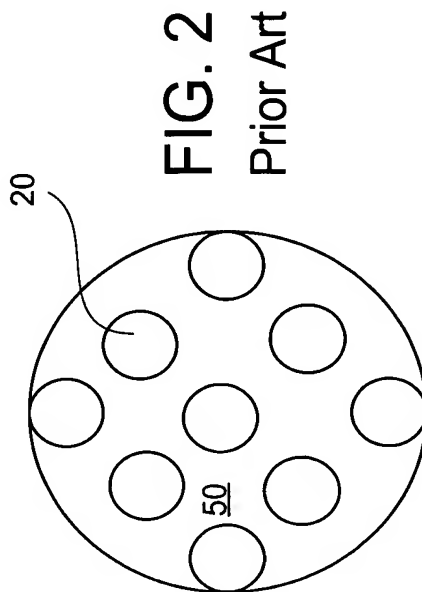
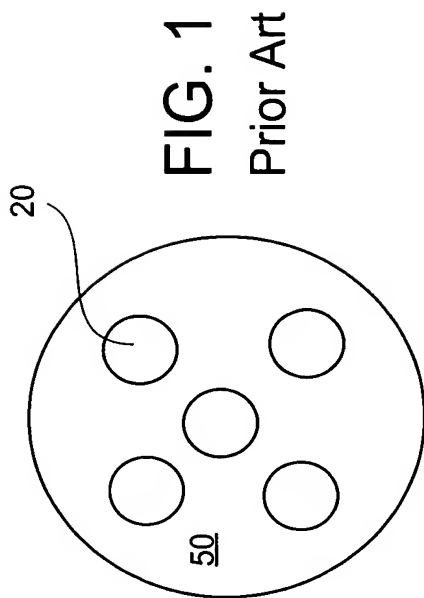


Title: METHOD AND APPARATUS FOR MEASUREMENT OF THIN FILMS
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Inventor: Yehiel Gotkis

Docket No: LAM2P466 App. No: 10/810,209



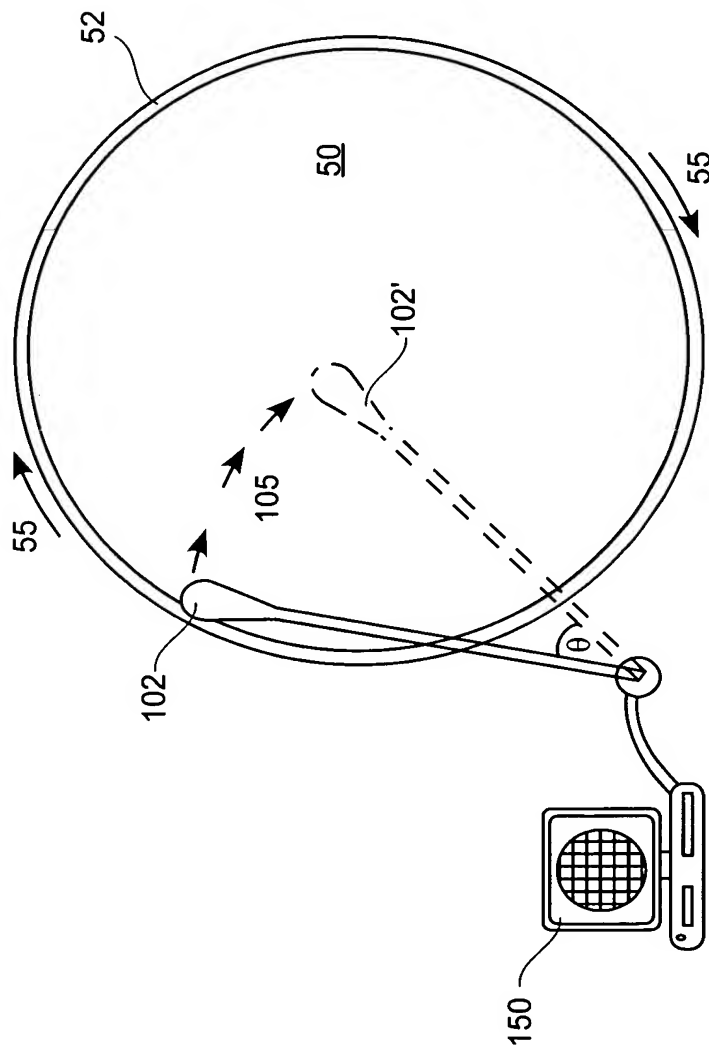


FIG. 3



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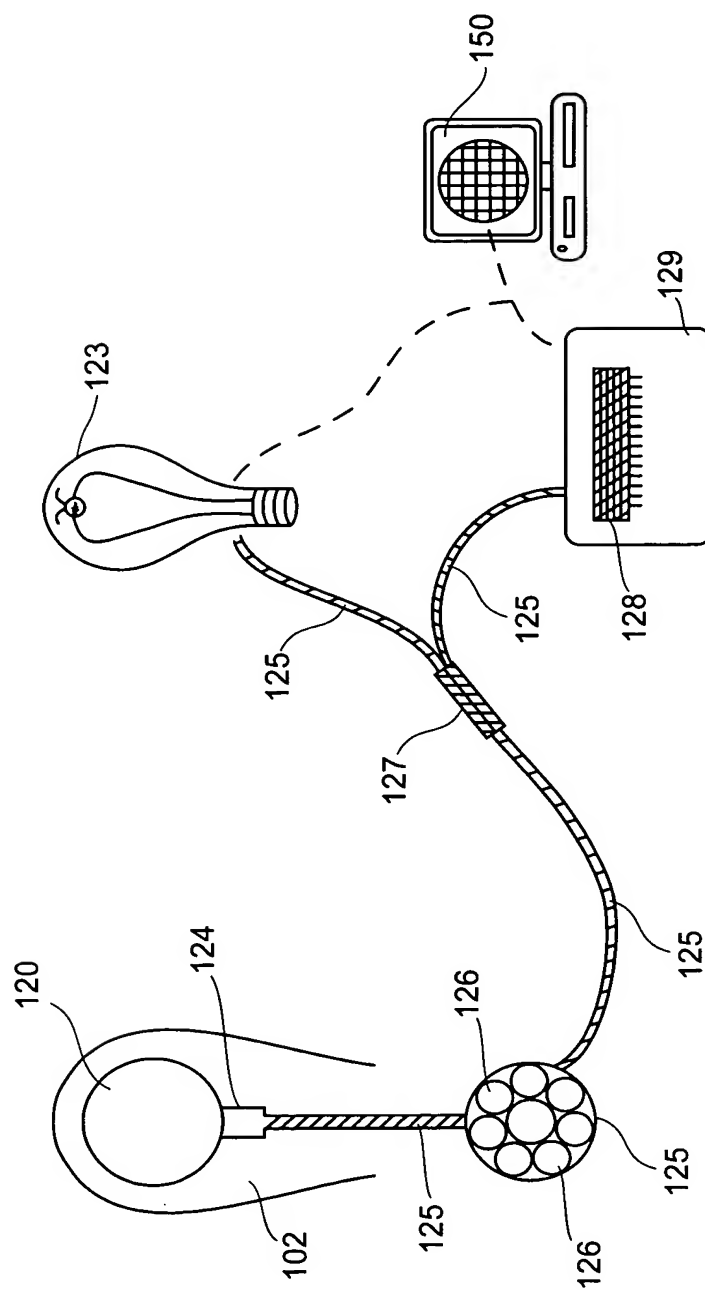


FIG. 5A-1

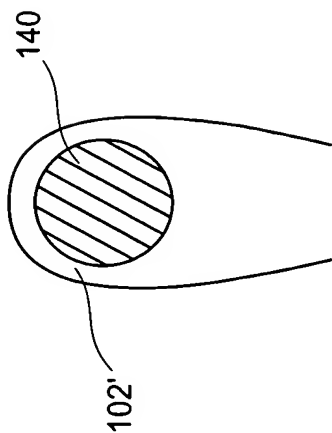


FIG. 5A

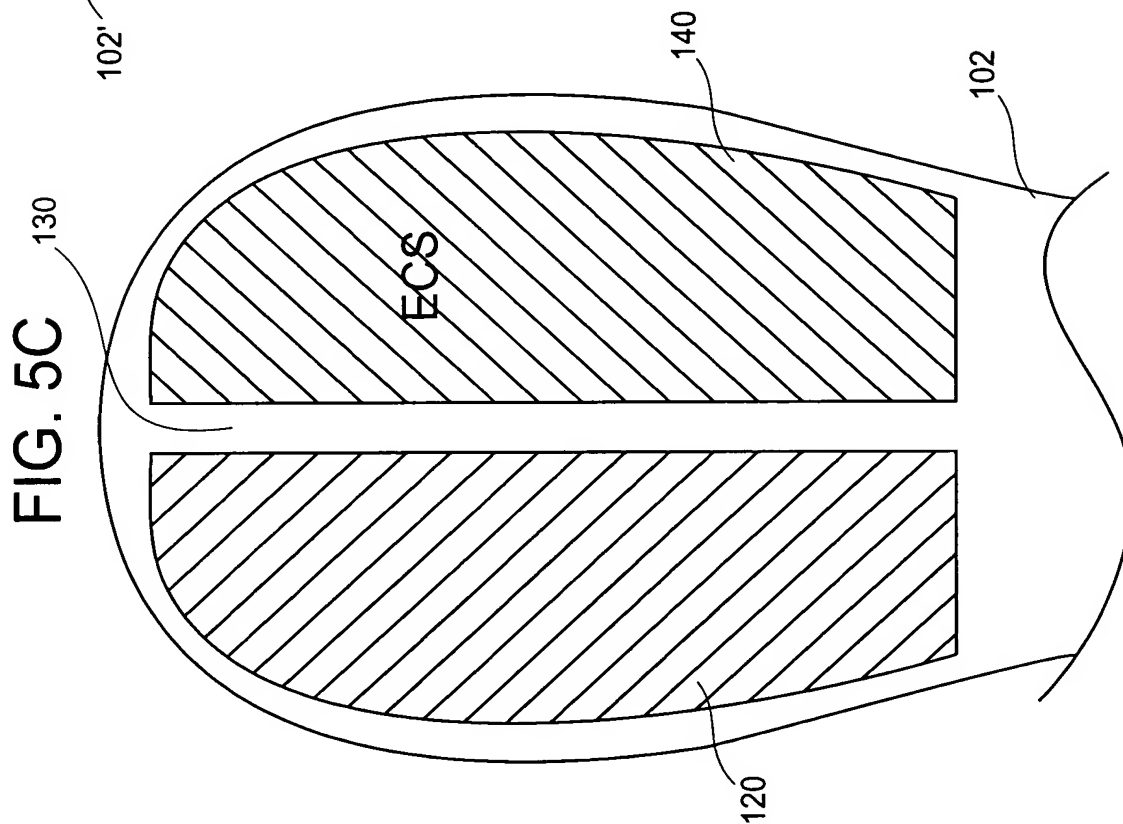


FIG. 5C

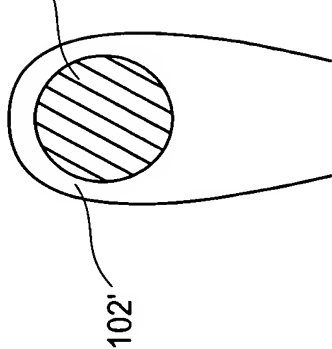


FIG. 5B

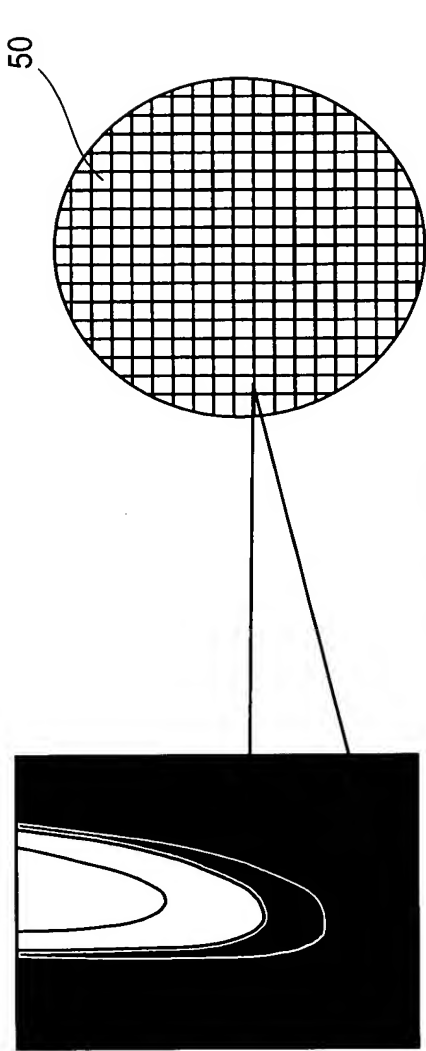


FIG. 6A

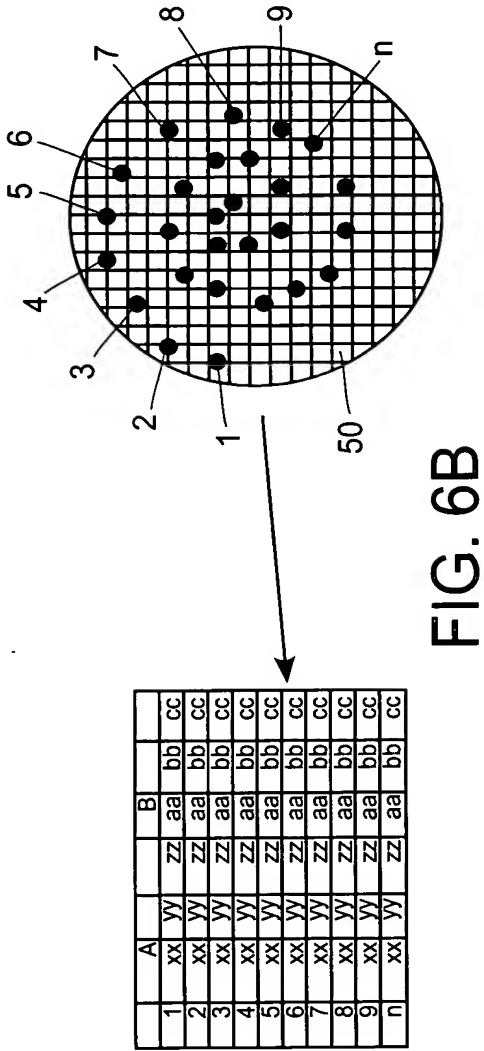


FIG. 6B

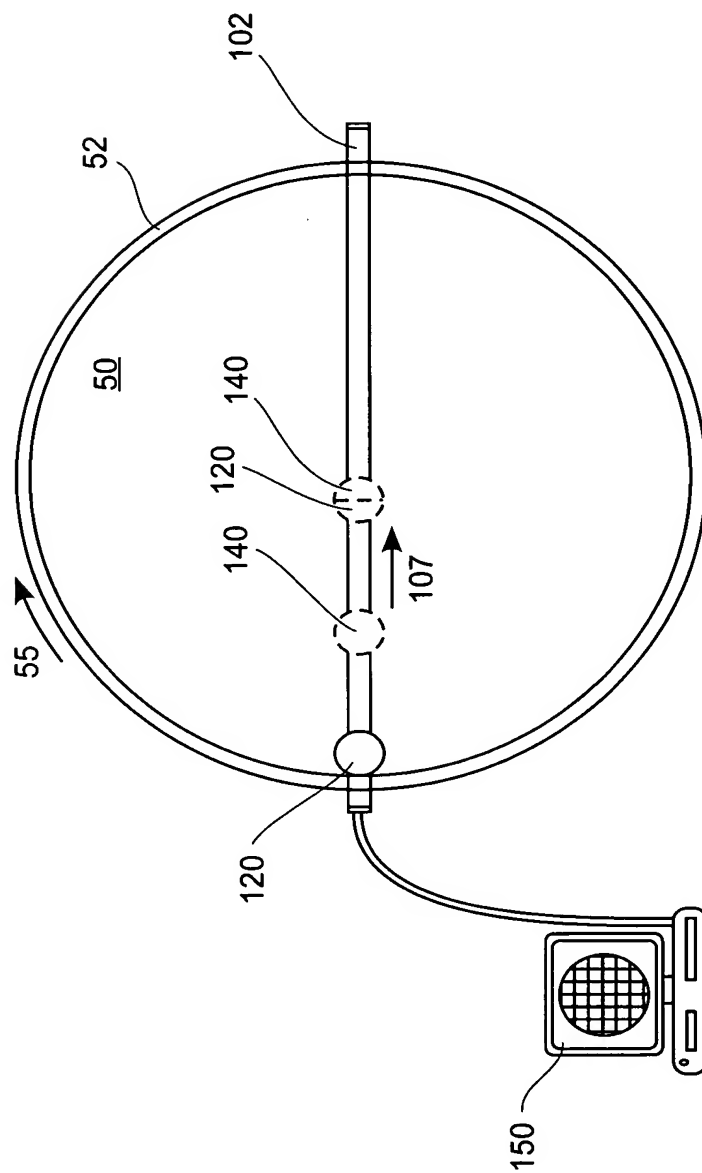


FIG. 7

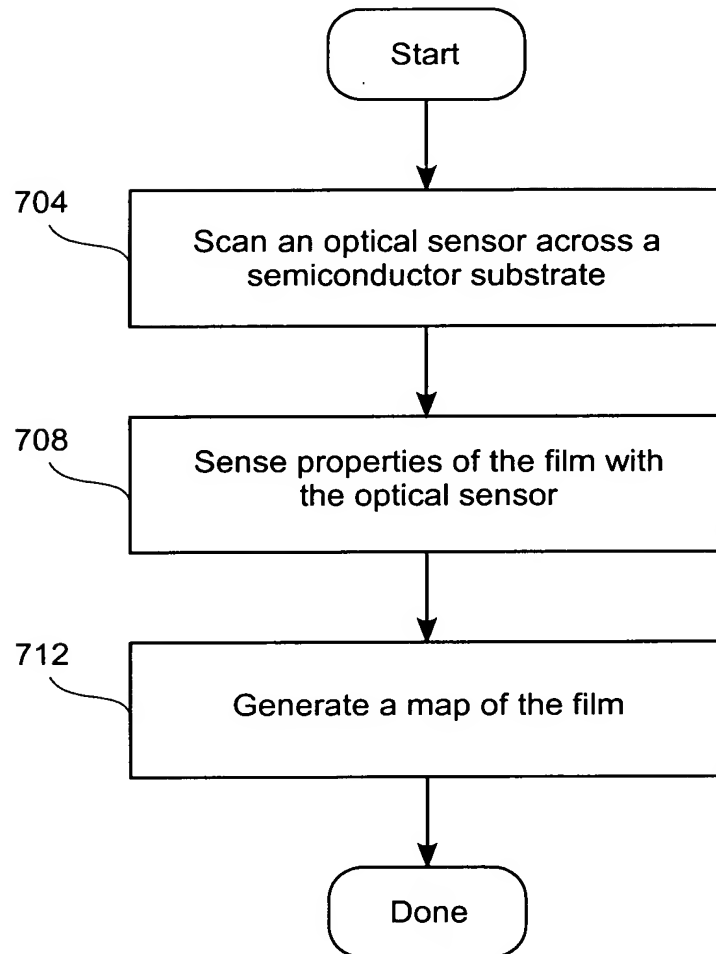


FIG. 8

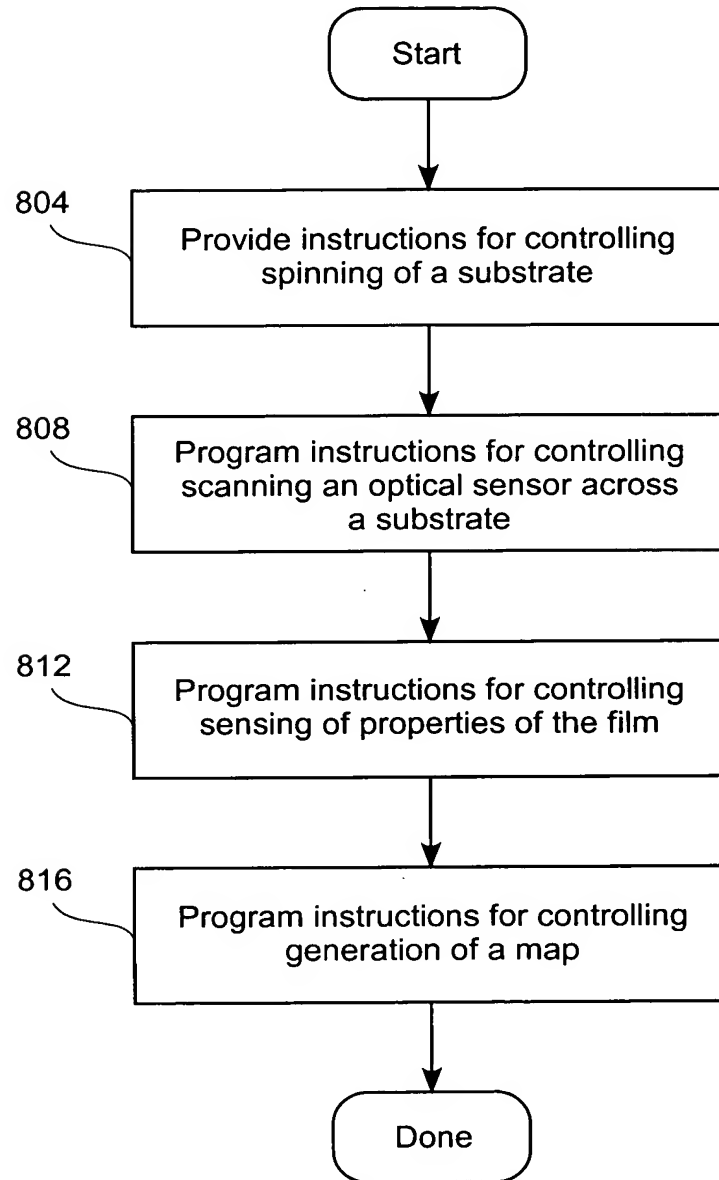


FIG. 9